

**IN THE CLAIMS:**

1. (currently amended) A power transistor comprising ~~composed of~~  
a plurality of vertical PNP transistors formed on a P-type silicon substrate, wherein  
the vertical PNP transistors have an N<sup>+</sup> type electrode layer,  
a ~~singularity or~~ plurality of electrode portions of an N<sup>+</sup> type buried layer formed to  
isolate the P-type silicon substrate and the plurality of vertical PNP transistors from each  
other ~~are provided in an active region of the power transistor, and~~  
an N<sup>+</sup> type diffusion layer sandwiched between at least two of the plurality of  
vertical PNP transistors as well as under, contacting and surrounding a portion of the N<sup>+</sup>  
type electrode layer, and extending to contact the N<sup>+</sup> type buried layer.

2. (original) The power transistor according to Claim 1, wherein  
at least part of the electrode portion is provided under common emitter metal lines of the power transistor routed on the active region of the power transistor.
3. (original) The power transistor according to Claim 1, wherein  
the electrode portions are provided on the  $N^+$  type buried layer and formed of an  $N^+$  type electrode layer for making ohmic contact and an  $N^+$  type diffusion layer.
4. (original) The power transistor according to Claim 3, wherein  
the  $N^+$  type diffusion layer is formed simultaneously with an  $N^+$  type base well layer as a base region of the plurality of vertical PNP transistors.
5. (original) The power transistor according to Claim 3, wherein  
the  $N^+$  type diffusion layer is formed at a range of dopant level of  $1 \times 10^{16}$  to  $1 \times 10^{17}$  atoms/cm<sup>3</sup>, which is heavier than that of an N-type epitaxial layer formed on the P-type silicon substrate.
6. (original) The power transistor according to Claim 3, wherein  
the  $N^+$  type diffusion layer is formed so that dopants are diffused until they reach the  $N^+$  type buried layer present on a bottom face of the power transistor.

7. (original) The power transistor according to Claim 1, wherein  
the singularity or plurality of electrode portions are placed so as to be  
uniformly spaced from their respectively adjacent electrode portions.

8. (original) A semiconductor integrated circuit characterized by using the  
power transistor as defined in Claim 1.

9. (currently amended) A power transistor having suppression of problematic leak  
current, the power transistor comprising:

a plurality of vertical PNP transistors formed on a P-type substrate, each PNP  
transistor having a  $P^+$  type collector, an  $N^+$  type base well formed at a base region, a  $P^+$   
type emitter layer and an  $N^+$  type base layer;

$P^+$  type collector buried layers formed under the  $N^+$  type base well;

an  $N^+$  type buried layer isolating the P-type substrate from the  $P^+$  type collector;

an N-type epitaxial layer formed over a surface of the P-type substrate;

an  $N^+$  type electrode layer; and

a plurality of  $N^+$  type diffusion layers formed at electrode portions within an active  
region just under, contacting and surrounding the  $N^+$  type electrode layer to reduce  
resistance of the N-type epitaxial layer by extending therethrough to contact the  $N^+$  type  
buried layer, wherein at least one of the  $N^+$  type diffusion layers passes between the  $P^+$   
type collector buried layers.